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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/072,145	02/07/2002	Guy E. Averett	ONS00317	1448
7	590 11/20/2002			
ON Semiconductor			EXAMINER	
Patent Administration Dept - MD A700 P.O. Box 62890 Phoenix, AZ 85082-2890			MAGEE, T	HOMAS J
			ART UNIT	PAPER NUMBER
		•	2811	
			DATE MAILED: 11/20/2002	

Please find below and/or attached an Office communication concerning this application or proceeding.

	Application No.	Applicant(s)				
	10/072,145					
· Office Action Summary	Examiner .	AVERETT ET AL.				
,	Thomas J. Magee	Art Unit				
Th MAILING DATE of this c mmunication a		2811 correspondenc address				
Period for Reply		•				
A SHORTENED STATUTORY PERIOD FOR REF THE MAILING DATE OF THIS COMMUNICATION - Extensions of time may be available under the provisions of 37 CFR after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a r - If NO period for reply is specified above, the maximum statutory perion - Failure to reply within the set or extended period for reply will, by state - Any reply received by the Office later than three months after the main earned patent term adjustment. See 37 CFR 1.704(b). Status	J. 1.136(a). In no event, however, may a reply be eply within the statutory minimum of thirty (30) d will apply and will expire SIX (6) MONTHS fro ute. cause the application to become ABANDO!	timely filed days will be considered timely. om the mailing date of this communication. NED (35 U.S.C. & 133)				
1) Responsive to communication(s) filed on $\underline{1}$	<u> 2 September 2002</u> .					
2a) ☐ This action is FINAL . 2b) ☑	This action is non-final.					
3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213. Disposition of Claims						
4)⊠ Claim(s) <u>1-25</u> is/are pending in the application.						
4a) Of the above claim(s) <u>12-25</u> is/are withdrawn from consideration.						
5) Claim(s) is/are allowed.						
6)⊠ Claim(s) <u>1-11</u> is/are rejected.						
7) Claim(s) is/are objected to.						
8) Claim(s) are subject to restriction and Application Papers	or election requirement.					
9)☐ The specification is objected to by the Examir	ner.					
10)☐ The drawing(s) filed on is/are: a)☐ accepted or b)☐ objected to by the Examiner.						
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).						
11) ☐ The proposed drawing correction filed on is: a) ☐ approved b) ☐ disapproved by the Examiner.						
If approved, corrected drawings are required in reply to this Office action.						
12) The oath or declaration is objected to by the Examiner.						
Pri rity under 35 U.S.C. §§ 119 and 120						
13) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).						
a) All b) Some * c) None of:						
 1. Certified copies of the priority documents have been received. 2. Certified copies of the priority documents have been received in Application No 						
 3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)). * See the attached detailed Office action for a list of the certified copies not received. 						
14) ☐ Acknowledgment is made of a claim for domes	·					
a) ☐ The translation of the foreign language p 15)☐ Acknowledgment is made of a claim for domes	rovisional application has been re	eceived.				
Attachment(s)						
 Notice of References Cited (PTO-892) Notice of Draftsperson's Patent Drawing Review (PTO-948) Information Disclosure Statement(s) (PTO-1449) Paper No(s) 	5) Notice of Informa	ary (PTO-413) Paper No(s) Il Patent Application (PTO-152)				
S. Patent and Trademark Office PTO-326 (Rev. 04-01) Office A	Action Summary	Part of Paper No. 7				

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DETAILED ACTION

Election/Restrictions

Applicant's election without traverse of Claims 1 – 11 in Letter No. 5 of September
 2002 is acknowledged.

Objections

2. The drawings are objected to under 37 CFR 1.83(a). The drawings must show every feature of the invention specified in the claims. In Figures 4 and 6, the "extra" layer (right side trench) lining the trench adjacent to the layer, 95, is not recited in the specification or in the claims. The origin or nature of this extra layer is unknown to Examiner. A proposed drawing correction or corrected drawings are required in reply to the Office action to avoid abandonment of the application.

Claim Rejections - 35 U.S.C. 103

- 3. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office Action:
- (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 4. Claims 1 11 are rejected under 35 U.S.C. 103(a) as being unpatentable over Lur et al. '041 (US 5,640,041) in view of Lur et al. '786 (US 5,308,786).

Lur et al. '041 disclose a semiconductor device formed in a monocrystalline silicon sub-

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strate (Col. 3, line 67) where a second recessed region (22) (See Figure 6) is formed within a first recessed region (15,16) etched from a deposited silicon dioxide layer (Col. 4, lines 53 - 55) and the surface of trenches covered with silicon dioxide (CVD) (cap layer) to seal the "voids" or trenches (Col. 3, lines 10 – 15). The walls of trenches are covered with silicon dioxide (25) (See Figure 10).

Lur et al. '041 do not disclose that the second dielectric material (SiO2) is thermally grown. However, for this application, a thermally grown and CVD silicon dioxide layer are functionally equivalent in terms of a sealant atop trenches.

An active device is formed in an active region (See Figure 14) with a gate dielectric (4), gate electrode (5), and doped regions (52,54) (n+,n-) at the peripheral edges. An electrical (passive) component comprised of a bonding pad or electrode (5) over a dielectric region (3) containing "voids" is formed with electrical contacts (56) at the top.

Lur et al. '041 do not explicitly disclose the depth of trenches in the second recessed region. However, Lur et al. '786 disclose (Col. 4, lines 54 – 57) in a similar device for the narrow trenches (17) (See Figure 6) that the depth is 20,000 Angstroms (2um), which is consistent with the depth recited in the instant application, subject to optimization for a particular device application. Therefore, it would have been obvious to one of ordinary skill in the art at the time of the invention to combine Lur et al. '786 with Lur et al. '041 to obtain recesses of adequate depth for optimization of device parameters.

Conclusions

Any inquiry concerning this communication or earlier communications from the

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Examiner should be directed to **Thomas Magee**, whose telephone number is **(703)** 305 5396. The Examiner can normally be reached on Monday through Friday from 8:30AM to 5:00PM (EST). If attempts to reach the Examiner by telephone are unsuccessful, the examiner's supervisor, **Tom Thomas**, can be reached on **(703)** 308-2772. The fax number for the organization where this application or proceeding is assigned is **(703)**

308-7722.

Thomas Magee November 12, 2002 TOM THOMAS SUPERVISORY PATENT EXAMINER TECHNOLOGY CENTER 2800